## Notice of References Cited

Application/Control No. Applicant(s)/Patent Under Reexamination 10/567,138 SALVERMOSER ET AL. Examiner Art Unit Page 1 of 1 MICHAEL MASKELL 2881

## U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	Α	US-5,729,565 A	03-1998	Meller et al.	372/87
*	В	US-6,052,401 A	04-2000	Wieser et al.	372/74
*	С	US-6,282,222 B1	08-2001	Wieser et al.	372/74
*	D	US-2002/0031157 A1	03-2002	Heist et al.	372/55
*	Е	US-6,400,089 B1	06-2002	Salvermoser et al.	315/111.81
*	F	US-2002/0101902 A1	08-2002	Albrecht et al.	372/58
*	G	US-6,563,853 B2	05-2003	Heist et al.	372/57
	Н	US-			
		US-			
	J	US-			
	К	US-			
	٦	US-			
	м	US-			

## FOREIGN PATENT DOCUMENTS

FOREIGN FATENT DOCUMENTS								
*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification		
	N							
	0							
	Р							
	Q							
	R							
	s							
	т							

## NON-PATENT DOCUMENTS

	NOTE ATENT DOCUMENTO						
*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)					
	U	El-Habachi, et al ("Emission of excimer radiation from direct current, high-pressure hollow cathode discharges" Appl. Phys. Lett. Vol. 72., No. 1, pp. 22-24, 5 January 1998).					
	v	Switkes, et al "Imaging of 1-nm-thick films with 193-nm microscopy," Optics Letters, 26:15 pp. 1182-1184, August 1, 2001.					
	w						
	x						

A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.